High-Efficiency focusing grating coupler with distributed Bragg reflector

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9 Abstract: We propose a high-efficiency silicon nitride focusing grating coupler with a bottom 10 reflector. The bottom reflector consists of a distributed Bragg reflector (DBR) with a stack of 11 Si₃N₄ and SiO₂ layers. Moreover, the taperless structure of focusing grating couplers is utilized 12 to further increase the density of integration. The result shows that the reflectivity of the grating coupler with 8-layer DBR reaches 98% at 1550nm, the peak coupling efficiency (CE) is -2.1dB 13 14 and the 1dB bandwidth is 66nm. Compared to the focusing grating without DBR, the CE is 15 improved by 1.87 dB with slight change in 1dB bandwidth, and the footprint is only $27.1 \times$ 16 37.1µm².

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19 **1. Introduction**

Loss reduction is one of the most essential and emergent issues that should be tackled in
photonic integrated circuits (PICs). Due to its low-loss property and transparency across a broad
wavelength range (400-2350nm), silicon nitride (Si₃N₄) has been considered as a promising
platform[1-5]. It has been widely used in communication[6], sensing[7], computation[8] and
quantum physics[9].

25 Lots of optical coupling methods have been already utilized, however, the low-loss optical 26 coupling is still a serious challenge in Si₃N₄ platform. The grating coupler (GC) is one of the 27 most commonly used coupling methods to achieve flexible wafer-scale testing[10-11]. The 28 coupling efficiency (CE) of grating couplers is mainly related to directionality and mode 29 mismatch. The Si₃N₄ GC has been proposed and fabricated in ref.[12], but the coupling 30 efficiency is only 27%, which is caused by the fact that most of the optical power is dissipated 31 downward into the substrate, resulting in poor directionality. To solve this problem, several 32 approaches have been proposed. Dual-level or silicon overlay in Si₃N₄ grating coupler has been 33 reported to improve the directionality, but the complexity is significantly increased[13-14]. And 34 the other approach is using bottom reflectors such as metal mirrors or distributed Bragg 35 reflectors (DBR) to cover the light scattered towards the substrate. However, the metal mirror 36 is fragile at high temperatures and the fabrication process of reflectors is relatively complex 37 and incompatible with CMOS fabrication[15-16].

In this paper, a high-efficiency focusing Si₃N₄ grating coupler is proposed. In order to improve the directionality, a DBR consisting of a stack of silicon nitride and silicon dioxide is employed as the bottom reflector. The reflectivity can reach 98% with 8-layer DBR at a wavelength of 1550nm. Furthermore, a focusing grating instead of a linear grating is utilized to reduce the footprint, therefore, improve the integration density.

43 2. Simulation and design

44 The schematic of the proposed Si_3N_4 GC is shown in Fig. 1(a). In order to reduce P_{down} and

45 enhance directionality, a stack of the multilayer DBR is deposited on the Si substrate, and a 400

16 nm fully etched Si₃N₄ layer is deposited on the buried oxide (BOX) layer, a SiO₂ cladding layer

47 covers the Si_3N_4 GC to protect the device.



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53 2.1 Gratings on 400 nm Si₃N₄

Fig. 1(b) shows the structure diagram of the focusing grating coupler and the wave vector of the fan-shaped grating coupler at (z, y). In order to achieve the phase of constructive interference, the following requirements should be met:

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$$K_{\text{in,z}}\cos\alpha r + 2\pi m = K_{\text{GC}}r \qquad (2-1)$$

58 where K_{GC} is the wave vector of the waveguide, α is the angle between the connection vector

- 59 of (z, y) and the center of the circle (0, 0) and the z-axis, $r = \sqrt{z^2 + y^2}$ is the distance from (z, z)
- 60 y) to (0, 0), m is an integer number, $K_{in,z} = (2\pi n_c \cdot sin\varphi)/\lambda$ is the projected component of the

61 incident wave vector in the grating plane, n_c is the refractive index of cladding material, λ is 62 the center wavelength, $K_{\rm GC} = (2\pi n_{\rm eff})$ is the wave vector size of the grating waveguide, $n_{\rm eff}$ 63 is the effective index of the grating. To satisfy the Bragg condition at first order:

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$$_{\rm eff} - n_{\rm c} \cdot \sin \varphi = \frac{\lambda}{\Lambda} \tag{2-2}$$

65 where Λ is the period of grating coupler, φ is the coupling angle, n_{eff} is calculate as: 66

$$n_{\rm eff} = ff \cdot n_{\rm eff1} + (1 - ff) \cdot n_{\rm eff2} \tag{2-3}$$

67 where ff is the filling factor defined as the ratio of grating teeth to the period, n_{eff1} is the 68 refractive index of the grating teeth and n_{eff2} is the refractive index of the etched region.

69 The finite-difference time-domain (FDTD) has been used to optimize GC structures. Fig. 70 1(c) shows various power distribution, P_{up}/P_{down} represent the upward/downward power and 71 $P_{\rm T}/P_{\rm R}$ is the transmit/reflect power. Fig. 2(a) shows coupling efficiency as a function of the 72 filling factor. The fill factor affects the performance of a grating coupler by changing the 73 effective index, via Equation (2-2). Hence, as the fill factor increases, the effective index 74 increases. The result shows that ff=0.5 is optimal. The spectra of grating couplers with different 75 periods (Λ) are shown in Fig. 2(b). The grating period is the parameter with the most impact on 76 the grating wavelength, as seen by Equation (2-2). As the grating period varied from $1.03\mu m$ 77 to $1.05\mu m$, the central wavelength of the grating coupler shifted from 1537nm to 1558nm. The 78 wavelength has a red shift as the period increases. According to Eq.(2-2), the coupling 79 efficiency is related to coupling angle (φ). When ff=0.5 and $\Lambda=1.04\mu$ m, CE with different φ is 80 shown in Fig. 2(c). The wavelength has a blue shift as coupling angle increases. Therefore, 81 $\varphi = 11^{\circ}$ is chosen to achieve the maximum coupling efficiency of -3.97dB at $\lambda = 1550$ nm.



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Fig. 2. (a) The coupling efficiency as a function of the filling factor; (b) The coupling efficiency as a function of the period of GC; (c) The coupling efficiency as a function of coupling angle; (d) The optimized power distribution of various transmission directions with the period of 1.04µm and fill factor of 0.5.

86 Fig. 2(d) shows the spectral response with a period of $1.04\mu m$ and a fill factor of 0.5. 87 Although the grating period and the filling factor have been optimized, the substrate leakage 88 P_{down} accounts for a substantial portion of the total scattered power loss. In order to reduce P_{down} 89 and enhance directionality, the bottom reflector using multiple DBR stacks is proposed.

90 2.2 Design of DBR

91 Each layer of DBR consists of a high-index material Si₃N₄ and a low-index material SiO₂, the

92 thickness of Si₃N₄ and SiO₂ are calculated according to $\lambda/4n$ [18] (λ is the center wavelength

- 93 of the source and n is the refractive index of materials), so after calculation the thickness of Si N and SiO mag act as 104 nm and 268 nm magnetization
- 94 Si_3N_4 and SiO_2 was set as 194 nm and 268 nm, respectively.



Wavdength(µm)
Fig. 3 (a) Reflectivity as a function of the wavelength when the DBR reflection layer is 2, 4, 6, and 8, respectively; (b)
Reflectivity as a function of the layers when wavelength at 1550nm; (c) Reflectivity with SiO₂ film thickness variation when Si₃N₄ thickness is 194 nm; (d) Reflectivity with Si₃N₄ film thickness variation when SiO₂ thickness is 268 nm, while the thickness variation scanning step is 10nm.

100Fig. 3(a) shows the reflectivity as a function of wavelength with the different numbers of101layers N of DBR. As shown in Fig. 3(b), as the increase of N, the reflectivity increases slowly.102When N=8, the reflectivity almost can keep at a constant 96.7% for wavelength ranging from1031400nm to 1600nm. As shown in Fig. 3(c) (d), the reflectivity spectrum varies slightly with the104thickness of SiO2 film and Si₃N₄ film, respectively, i.e., large fabrication tolerance.

105 2.3 Design of BOX



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Fig. 4. Coupling efficiency as a function of BOX thickness.

108 BOX layer is utilized to prevent mode leakage, and a specific BOX thickness can achieve 109 constructive interference between the reflected light and the directly upward radiated light, 110 thereby reducing the loss. Therefore, the thickness of the BOX layer between the grating and 111 the reflector needs to be calculated and optimized. Fig. 4 shows that the coupling efficiency is 112 highly dependent on the BOX thickness(H_{box}). Form calculation, H_{box} =1.448 µm is set to 113 achieve the constructive interference.

114 2.4 Impact of DBR Stacks



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Fig. 5. Comparison of coupling spectrum between without and with the DBR stacks.

Fig. 5 shows the comparison of the coupling spectrum without and with the DBR stack,
which are -3.97dB and -2.1dB, and the 1dB bandwidth reaches 66nm, which is much larger
than that of the Sillion grating coupler. Moreover, the influence of DBR on the bandwidth can
be neglected. From the comparison, table 1, our proposed focusing grating shows quite great
performance.

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 Table 1. Comparison of the performance of different SiN grating couplers

Ref.	Bottom reflector	Gratings	Max CE (dB)	1dB Bandwidth(nm)	t _{sin} (nm)	Footprint (µm)
[17]	Si-SiO ₂	linear grating	-2.5	53	400	13×530
[18]	α -Si-SiO ₂	linear grating	-2.29	49	500	$12 \times $

[18]	α -Si-SiO ₂	linear grating	-2.58	52	400	$12 \times $
[16]	SiNx-SiO ₂	linear grating	-2.4	52.5	325	13×530
[19]	AlCu/TiN	focusing gratings	-2.29	1	100	28×100
This work	Si_3N_4 - SiO_2	focusing gratings	-2.1	66	400	27.1×37.1

123 3. Conclusion

124 In conclusion, a high-efficiency focusing Si₃N₄ grating coupler with DBR is demonstrated. The 125 directionality of GC is optimized by adding DBR consisting of a stack of silicon nitride and 126 silicon dioxide as the bottom reflector, and the fan-shape focusing grating is used to improve 127 the density of integration. The result shows that the reflectivity reaches 98% at a wavelength of 128 1550nm. The peak coupling efficiency is -2.1dB the bandwidth is 66nm, and the footprint is 129 only $27.1 \times 37.1 \mu m^2$. The performance of the grating coupler can be further improved by 130 optimizing its filling factor.

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